



Trends and Prospects in Computer Vision and Pattern Recognition Technology

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Deadline for manuscript
submissions:

20 July 2024

Message from the Guest Editors

Computer vision and pattern recognition technology are great of importance for the evolution of artificial intelligence, as well as for the development of applications in various areas, including medical diagnosis, robotics, autonomous driving, 3D reconstruction, sentiment and emotion analysis, decision-making systems and many other domains.

This Special Issue aims to present and discuss the recent advancements, trends and applications in the broad field of computer vision and pattern recognition, as well as to review our present perspectives. It will cover fundamental and applied aspects of this topic.

We invite researchers from various fields to contribute to this Special Issue. We aim to inspire new approaches and applications of computer vision and pattern recognition.

In this Special Issue, we will publish high-quality papers in the overlapping fields of:

- Medical image processing;
- Machine learning theory;
- 3D reconstruction;
- Object detection and image segmentation;
- Video processing;
- Robotics;
- Decision-making systems;
- Semantic analysis.





an Open Access Journal by MDPI

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Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal Applied Sciences has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multi-dimensional network.

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